

depositing a coating on the substrate over at least a portion of the ion beam milled surface thereof.

*B1
andrew*
40. (New) The method of claim 39, wherein said ion beam milling is performed so as to reduce the thickness of substantially the entire substrate by from about 4-20 Å.

41. (New) The method of claim 39, wherein the ion beam milling is performed using an ion energy of from about 1500-2000 eV.

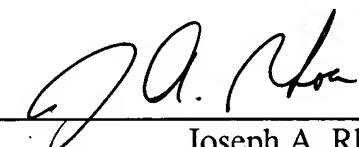
REMARKS

This is a continuation of Serial No. 09/703,709. The original claims have been canceled, and new claims 39-41 have been added. It is respectfully requested that the application be amended as set forth above prior to initial examination thereof.

Respectfully submitted,

NIXON & VANDERHYE P.C.

By:


Joseph A. Rhoa
Reg. No. 37,515

JAR:caj
1100 North Glebe Road, 8th Floor
Arlington, VA 22201-4714
Telephone: (703) 816-4000
Facsimile: (703) 816-4100